Abstracts

Suspended Membrane Inductors and Capacitors for Application in Silicon MMIC's

Y. Sun, H. van Zeijl, J.L. Tauritz and R.G.F. Baets. "Suspended Membrane Inductors and Capacitors for Application in Silicon MMIC's." 1996 Microwave and Millimeter-Wave Monolithic Circuits Symposium Digest 98. (1996 [MCS]): 99-102.

This paper considers the fabrication and modelling of suspended membrane inductors and capacitors on ordinary Silicon substrates. A single post-processing etching step was added to an otherwise standard process. For both components, parasitic capacitances to ground are drastically reduced, enabling high frequency operation. Furthermore, the measured quality factor Q is demonstrably improved with respect to normally fabricated thin film components.

❑ Return to main document.